IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Hajime YAMAMOTO et al.

Art Unit: 1795

Application Number: 10/647,247

Examiner: Daborah Chacko Davis

Filed: **August 26, 2003**

Confirmation Number: 1773

For: METH

METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, AND

METHOD OF FORMING RESIST PATTERN

Attorney Docket Number:

031029

Customer Number:

38834

AMENDMENT UNDER 37 C.F.R. § 1.114

Mail Stop: RCE

February 4, 2010

Commissioner for Patents P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

This Submission is being filed concurrently with a Request for Continued Examination pursuant to 37 C.F.R. § 1.114, and is also being filed in response to the Final Office Action dated December 11, 2009.

Amendments to the Claims begin on page 2 of this paper.

Remarks begin on page 9 of this paper.